

FORM PTO-1449	SEP 03 2002 U.S. PATENT & TRADEMARK OFFICE	Atty. Docket No. SEN-019	Serial No. 10/074,561
LIST OF PRIOR ART CITED BY APPLICANT		Applicant: Abdurrahman Sezginer et al.	
		Filing Date: February 12, 2002	Group: 2881

U.S. PATENT DOCUMENTS

Examiner Initial*	Document Number	Grant Date	Name	Class	Sub Class	Filing Date
ZJ	AA 4,103,998	08/01/78	Nakazawa et al.	356	152	
ZJ	AB 4,172,664	10/30/79	Charsky et al.	356	356	
	AC 4,200,395	04/29/80	Smith et al.	356	356	
	AD 4,311,389	01/19/82	Fay et al.	356	354	
	AE 4,332,473	06/01/82	Ono	356	356	
	AF 4,703,434	10/27/87	Brunner	364	488	
	AG 4,757,207	07/12/88	Chappelow et al.	250	491.1	
	AH 5,100,237	03/31/92	Wittekoek et al.	356	401	
	AI 5,343,292	08/30/94	Brueck et al.	356	363	
ZJ	AJ 5,608,526	03/04/97	Piwonka-Corle et al.	356	369	

FOREIGN PATENT DOCUMENTS

Examiner Initial*	Publ. Number	Publ. Date	Country	Class	Sub Class	Translation Yes No
ZJ	AK WO99/45340	09/10/99	PCT			X

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

ZJ	AL	N.T. Sullivan et al., "Semiconductor Pattern Overlay", Handbook of Critical Dimension Metrology and Process Control, Proceedings of Conf. 28-29 Sept. 1993, Monterey, CA, K.M. Monahan, SPIE Optical Engineering Press, Vol. CR52, pp. 160-188.
	AM	Printout, Nikon KrF Step-and-Repeat Scanning System NSR-S205C, July 2000.
	AN	A. Starikov et al., "Accuracy of Overlay Measurements: Tool and mark Asymmetry Effects", Optical Engineering, June 1992, Vol. 31, No. 6, pp. 1298-1310.
ZJ	AO	J. Opsal et al., "Broadband Spectral Operation of a Rotating-Compensator Ellipsometer", Thin Solid Films, 1998, Vol. 313-314, pp. 58-61.

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[Signature]

DATE CONSIDERED:

12/9/03

*Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

FORM PTO-1449	Atty. Docket No. SEN-019	Serial No. 10/744,561
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LIST OF PRIOR ART
CITED BY APPLICANT

Applicant:
Abdurrahman Sezginer et al.

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Group:
2881

U.S. PATENT DOCUMENTS						
Examiner Initial*	Document Number	Grant Date	Name	Class	Sub Class	Filing Date
BA	5,721,607	02/24/98	Ota	355	53	
BB	5,808,742	09/15/98	Everett et al.	356	363	
BC	5,867,276	02/02/99	McNeil et al.	356	445	
BD	5,889,593	03/30/99	Bareket	356	445	
BE	5,963,329	10/05/99	Conrad et al.	356	372	
BF	6,023,338	02/08/00	Bareket	356	401	
BG	6,079,256	06/27/00	Bareket	73	105	
BH	6,088,103	07/11/00	Everett et al.	356	355	
BI	6,100,985	08/08/00	Scheiner et al.	356	381	
BJ	6,150,231	11/21/00	Muller et al.	438	401	

FOREIGN PATENT DOCUMENTS

Examiner Initial*	Document Number	Grant Date	Country	Class	Sub Class	Translation Yes No
BK						

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

BL	X. Niu et al., "Specular Spectroscopic Scatterometry in DUV Lithography", SPIE, March 1999, Vol. 3677, pp. 159-168. ,
BM	R.M. Silver et al., "Overlay Metrology: Recent Advances and Future Solutions", Future Fab International, Issue 11, London, July 2001, 17 pages. .
BN	IBM Technical Disclosure Bulletin, March 1990, 90A 60854/GE8880210, pp. 170-174. ,
BO	

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